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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Group Art Unit: 2812  
Examiner: Stanetta D. Isaac

In Re PATENT APPLICATION of:

Applicant(s): Jun KANAMORI

Serial No.: 10/634,851

Filing Date: August 6, 2003

For: SEMICONDUCTOR DEVICE FABRICATION  
METHOD USING OXYGEN ION  
IMPLANTATION

Atty. Ref.: MAE 292

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) **AMENDMENT**  
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September 28, 2006

**Mail Stop Amendment**  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Madam:

In response to the Examiner's Action mailed on June 30, 2006, please  
amend the above-identified application as follows: